

ABSTRACT

METHOD AND APPARATUS FOR INTEGRATED CIRCUIT INSPECTION

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A system for inspection and collating substrates comprising a receiving rack in communication with a reflow oven; said receiving rack arranged to receive a plurality of substrates from said reflow oven; an inspection device for inspecting said substrates and recording a status of each inspected substrate; a collector for receiving said substrates
10 from said receiving rack, the collector including a racking device for collating the substrates according to the recorded status.

Figure 2B

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